

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: **Mitsushi FUJIKI**

Serial Number: **Not Yet Assigned**

Filed: **February 6, 2004**

**Customer No.: 38834**

For: **METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE**

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

February 6, 2004


Sir:

In compliance with 37 CFR 1.56, Applicant(s) call(s) to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,  
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Enclosures: PTO-1449; References (2)

<b>INFORMATION DISCLOSURE STATEMENT PTO-1449</b>	Attv. Docket No. <b>042068</b>	Serial No. New Appln.
	Applicant(s): <b>Mitsushi FUJIKI</b>	
	Filing Date: <b>February 6, 2004</b>	Group Art Unit:

### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA					
	AB					
	AC					
	AD					

### FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)
AE	9-53188	02/25/97	Japan
AF			Abstract & Discussed in the Spec.
AG			
AH			
AI			

### OTHER DOCUMENTS

AJ	Jpn. J. Appl. Phys. Vol. 36 (1997) pp. L154-L157, Part 2, No. 2A, 1 February 1997 Takeshi OHWAKI et al., Preferred Orientation in Ti Films Sputter-Deposited on SiO <sub>2</sub> Glass: The Role of Water Chemisorption on the Substrate
AK	
Examiner	Date Considered